

# Electrical conduction through MIM structures of evaporated $V_2O_5$ and $V_2O_5/B_2O_3$ amorphous thin films

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The electrical conduction through vacuum-evaporated thin films of  $V_2O_5$  and  $V_2O_5/B_2O_3$  in MIM structures has been investigated. The high-field behaviour of both types of film is in accordance with the Poole-Frenkel type of mechanism. The increase in  $B_2O_3$  content in co-evaporated  $V_2O_5/B_2O_3$  films results in a decrease in the conductivity of the composite films. This is attributed to the expansion of the resultant film structure due to the network-forming effect of  $B_2O_3$ . The co-evaporated thin films of  $V_2O_5/B_2O_3$  with a molar content of  $B_2O_3$  larger than 40% are observed to be unstable because of their hygroscopic nature.

## 1. Introduction

The semiconducting properties of amorphous transition metal oxides arise from hopping of unpaired electrons between transition metal ions in two different valence states [1]. Two types of localization processes occur in such materials. The first type is the result of strong interaction of unpaired electrons with the polar network leading to the formation of small polarons [2]. A polaron (an electron and its accompanying distortion) whose dimension is comparable to the lattice spacing is designated as a small polaron [3]. The second type of localization, known as Anderson localization [4], occurs due to structural disorder.

Morin [5] showed that the width of the 3d band decreases in the 3d oxide series from scandium to vanadium and it approaches zero for chromium oxide. Depending upon the width of the 3d band, conduction in these materials is attributed either to electrons in the 3d band of the transition metal or to electron transitions between cations of different valencies. The intermediate position of vanadium oxide in the series of 3d transition metal oxides has stimulated interest in their properties.

Heamers *et al.* [6] found the conduction through  $V_2O_5$  single crystals to be due to variable range hopping between defect levels situated in the neighbourhood of the Fermi level. Koffyberg and Benko [7] showed that the activation energy for the d.c. electronic conductivity of amorphous  $V_2O_5$  and some glasses containing  $V_2O_5$  obeys the relation as given by Killias [8]. Sanchez *et al.* [9, 10] observed that the electrical properties of amorphous  $V_2O_5$  obtained by splat cooling appear to be consistent with the small-polaron model of nearest neighbour hopping. Nadkarni and Shirodkar [11] have proposed that the electrical properties (d.c. as well as a.c.) of the Al/ $V_2O_5$ /Al structure could be explained by considering the crystallite-crystallite interfacial Schottky-type barrier which

exists because of granular nature of these films. No extensive work has been published on amorphous thin films of  $V_2O_5$  prepared by the evaporation technique.

Most of the semiconducting glasses based on  $V_2O_5$  contain so-called network formers such as  $P_2O_5$  and  $B_2O_3$ . Many authors [12-18] have investigated the electronic conduction processes through  $V_2O_5$ -based glass systems. In a glass containing  $V_2O_5$  and  $P_2O_5$ , as the oxygen ions adjacent to the vanadium ions may also have phosphorus ions as near neighbours, so the network forming may effect the conductivity [12]. Sharma *et al.* [19] were the first to investigate  $V_2O_5$ - $B_2O_3$  glass. They observed a decrease in electrical conductivity with increasing  $B_2O_3$  content. Culea and Nicula [20] also studied the electrical properties of  $V_2O_5$ - $B_2O_3$  glasses and proposed a small polaron model for the conduction.

The transition metal ions can enter a semiconducting glass in several oxidation states. Glasses based on  $V_2O_5$  are known to have both  $V^{5+}$  and  $V^{4+}$  ions present. For these glasses, the conduction process has been described as the motion of an electron from a  $V^{4+}$  site to a  $V^{5+}$  site where the extra electron is bound to the vanadium by the lattice polarization it induces, i.e. forms a small polaron. The electrical conductivity in such semiconducting glasses is critically dependent on the ratio of low to high oxidation states of transition metal ions present in the glass [13]. The d.c. conductivity at higher temperatures is found to be well described by

$$\sigma = \sigma_0 \exp(-W/kT) \quad (1)$$

but below room temperature,  $W$  (the activation energy), ceases to be constant and decreases gradually as the temperature drops [14].

Here the electrical conduction through amorphous thin films of  $V_2O_5$  and  $V_2O_5/B_2O_3$  prepared by the thermal evaporation technique has been investigated.

## 2. Experimental procedure

The samples for electrical measurements were deposited on 3 in.  $\times$  1 in. ( $\sim 7.62$  cm  $\times$  2.54 cm) Corning 7059 borosilicate glass slides. In order to prepare MIM sandwiches, a metal strip was evaporated as the base electrode followed by mixed oxides from separate sources as insulator using the co-evaporation technique of Hogarth and Wright [21], and finally evaporating metal for the top electrodes. The rates of evaporation and film thickness could be controlled. Six devices, each having an effective area  $0.1$  cm<sup>2</sup>, were made on each substrate.

All electrical measurements were taken in a subsidiary vacuum system capable of producing a vacuum of  $10^{-6}$  torr ( $1.33 \times 10^{-4}$  Pa) and equipped with the necessary facilities. The device was firmly attached to the base of copper by pressure contacts, and electrical connections were made to the devices by means of copper strips joined with silver paste. A stainless steel tank incorporated into the top plate was used for low-temperature measurements by pouring liquid nitrogen into it. An insulated resistive wire made of molybdenum ribbon was inserted in the holes at the copper base and used as a heater element. The temperature measurements were made by attaching a chromel/alumel thermocouple to the substrate which was connected to a Comark electronic thermometer type 1601 Cr/A. The d.c. voltage-current characteristics were measured in a conventional manner. The circulating current was recorded by a Keithley 610C solid state electrometer.

## 3. Results

The  $I(V)$  characteristics for evaporated  $V_2O_5$  (300 nm) thin films is shown in Fig. 1. For low fields, the films

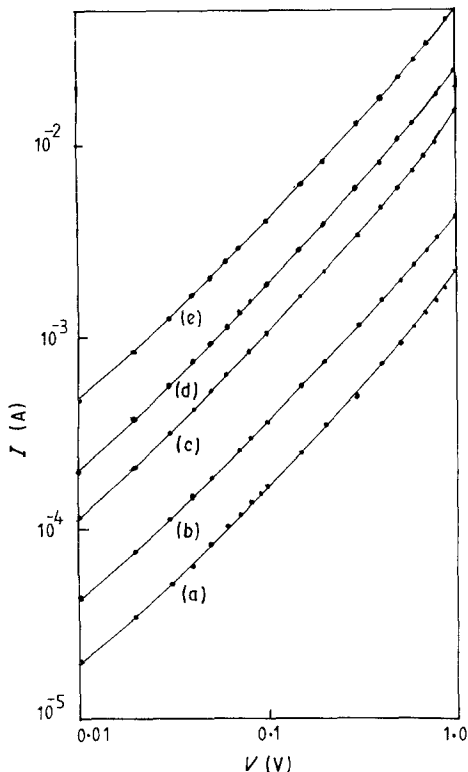


Figure 1  $I(V)$  characteristics for evaporated  $V_2O_5$  (300 nm) thin films at different temperatures: (a) 193 K, (b) 233 K, (c) 269 K, (d) 295 K, (e) 323 K.

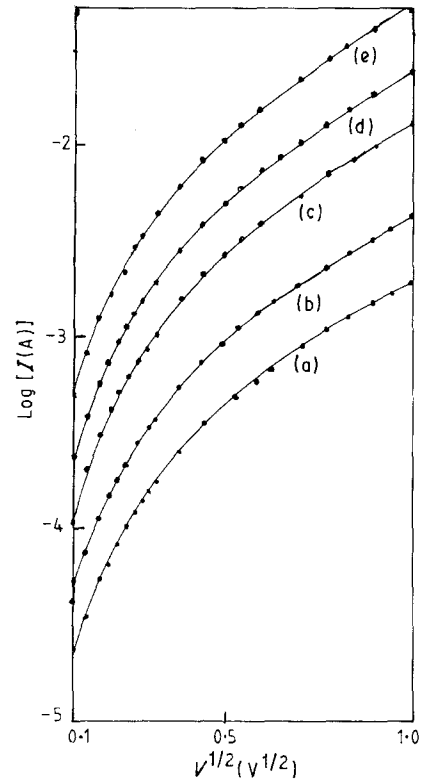


Figure 2 Data of Fig. 1 replotted as  $\log I$  against  $V^{1/2}$ .

show ohmic type of conduction whereas at higher fields they show non-ohmic behaviour. Fig. 2 shows the plot of  $\log I$  against  $V^{1/2}$  for the same sample as in Fig. 1. In order to calculate activation energy, electrical conductivity was plotted against inverse temperature as shown in Fig. 3 for the same sample as in Fig. 1. It can be seen that for low temperatures the activation energy is lower than at higher temperature indicating a different type of conduction process, compared to that at higher temperature.

Fig. 4 shows the  $I(V)$  characteristics for 70%  $V_2O_5$ /30%  $B_2O_3$  (300 nm) thin films prepared by the co-evaporation technique. The films show an exponential type of behaviour at higher field, whereas for lower fields their behaviour follow Ohm's law. The data of Fig. 4 replotted as  $\log I$  against  $V^{1/2}$  for the same sample as in Fig. 4 can be seen in Fig. 5. Fig. 6

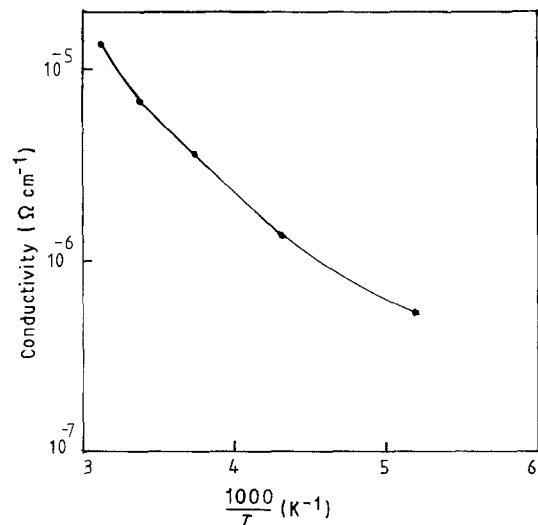


Figure 3 Conductivity plotted against inverse temperature for the same sample as in Fig. 1 at an applied voltage of 0.7 V.

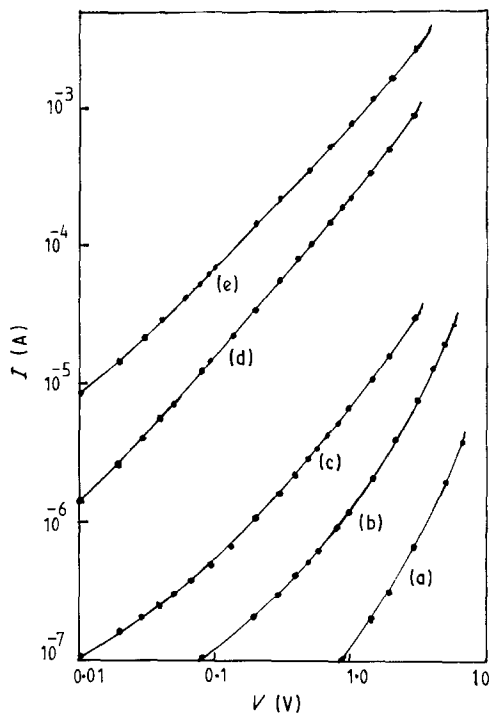
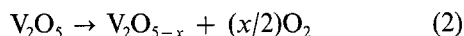


Figure 4  $I(V)$  characteristics for evaporated  $V_2O_5/B_2O_3$  (300 nm) thin films at different temperatures: (a) 193 K, (b) 223 K, (c) 253 K, (d) 293 K, (e) 327 K.

represents the plots of log conductivity against the inverse temperature.

#### 4. Discussion

Vanadium pentoxide is an oxygen-deficient semiconductor. The molten  $V_2O_5$  at the temperature just above the melting point dissociates according to the reaction



where  $x$  increases with the increasing temperature.

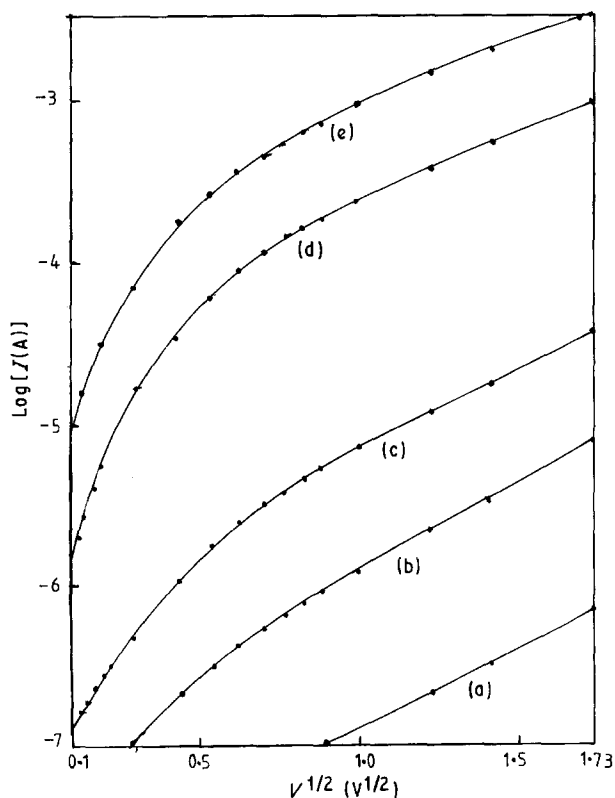


Figure 5 Data of Fig. 4 replotted as  $\log I$  against  $V^{1/2}$ .

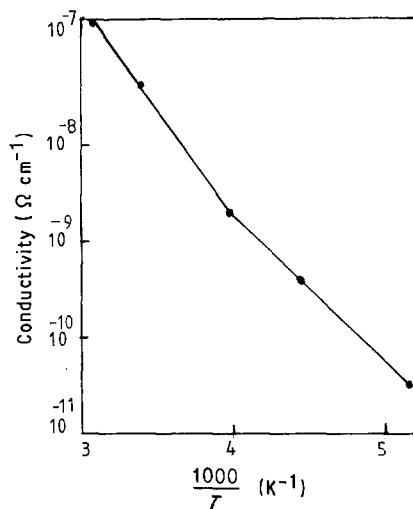
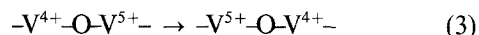


Figure 6 Conductivity plotted against inverse temperature for the same sample as in Fig. 4 at an applied voltage of 0.7 V.

For every oxygen atom evolved, two electrons are left behind. Among the many possibilities of electron behaviour, two were examined carefully: (a) the electrons are singly trapped at separate  $V^{5+}$  centres yielding two  $V^{4+}$  centres, and (b) the two electrons are trapped at one  $V^{5+}$  centre to yield one  $V^{3+}$  centre. The type (a) reaction is believed to be the most probable [22] because of the low energies involved.

Conduction in low-mobility transition metal oxides was originally considered to take place by a hopping mechanism [23]. Therefore, for  $V_2O_5$  an electron on a  $V^{4+}$  centre will move to a  $V^{5+}$  centre, the overall mechanism being formally represented by



The localization of an electron on a  $V^{4+}$  centre causes polarization of the surrounding lattice resulting in polaron formation.

Thus it is inferred that  $V^{4+}$  and  $V^{5+}$  are the two centres responsible for the electrical conduction through amorphous thin films of  $V_2O_5$ . It is reported by Dmitrieva *et al.* [24] that  $V_2O_5$  contains  $V^{4+}$  ions and their concentration is proportional to the conductivity. The presence of  $V^{4+}$  ions in  $V_2O_5$  is also supported by electron spin resonance (ESR) investigations [25]. It can be assumed that in evaporated  $V_2O_5$  amorphous thin films  $V^{4+}$  ions are present whose existence has been confirmed by our ESR investigations. The conduction process in the present samples may be governed by the hopping of electrons between  $V^{4+}$  and  $V^{5+}$  ions. Under the application of an electric field the barrier between  $V^{4+}$  and  $V^{5+}$  centres may be lowered and the transfer of charge between  $V^{4+}$  and  $V^{5+}$  centres may be increased.

The behaviour of the present samples as shown in Fig. 2 shows that the conduction process for higher fields indicates a barrier-lowering type of behaviour (Schottky or Poole-Frenkel effect) as

$$I \propto \exp(\beta E^{1/2}/kT) \quad (4)$$

where  $E$  is the applied field,  $k$  is the Boltzmann constant,  $T$  is absolute temperature and  $\beta$  is the barrier-lowering coefficient. In order to decide whether the conduction mechanism is Schottky or Poole-Frenkel

type, the experimental value of  $\beta$  can be compared with those of  $\beta_S$  or  $\beta_{PF}$ , respectively. The experimental value of  $\beta$  can be calculated with the help of Equation (1), i.e. from the curve between  $\log I$  and  $V^{1/2}$  for higher fields. The theoretical value of  $\beta$  is given by the expression

$$\beta = (e^3/n\pi\epsilon_0\epsilon_r)^{1/2} \quad (5)$$

where  $\epsilon_r$  is the high-frequency dielectric constant,  $n = 1$  for Poole–Frenkel effect and  $n = 4$  for the Schottky effect, and the other constants have their usual meanings. The experimental value of  $\beta$  at room temperature for  $V_2O_5$  (300 nm) thin films as calculated from the slope of the curve in Fig. 2 for higher values of fields is found to be  $2.1 \times 10^{-5} \text{ eV m}^{1/2} \text{ V}^{-1/2}$ . The theoretical value of  $\beta_{PF}$  as determined through Equation 2 for high-frequency (900 kHz) dielectric constant (11.8) at room temperature is  $2.2 \times 10^{-5} \text{ eV m}^{1/2} \text{ V}^{-1/2}$  whereas the value of  $\beta_S$  (theoretical) under the same conditions is  $1.1 \times 10^{-5} \text{ eV m}^{1/2} \text{ V}^{-1/2}$ . It is clear that the experimental value of  $\beta_{PF}$  is comparable with theoretical value of  $\beta$  where the experimental value of the  $\beta_S$  is twice the theoretical value of  $\beta$ . It is also observed that the experimental value of  $\beta$  is almost independent of temperature. Therefore, we propose that the conduction process through the MIM structure of evaporated  $V_2O_5$  thin films follows the Poole–Frenkel type of hopping of electrons from  $V^{4+}$  centres to  $V^{5+}$  centres. The activation energy of the evaporated thin films of simple  $V_2O_5$  has been calculated from the slope of the curve in Fig. 4 and is found to be 0.18 eV, which is consistent with the value as determined by Bullot *et al.* [26] for amorphous  $V_2O_5$  layers deposited from gels.

In the case of co-evaporated thin films of  $V_2O_5$  and  $B_2O_3$ , the network former oxide ( $B_2O_3$ ) expands the  $V_2O_5$  structure and the resulting  $V_2O_5/B_2O_3$  films become more disordered compared to those for simple  $V_2O_5$  under similar conditions. It is possible that the oxygen ions adjacent to vanadium ions may have boron ions as near neighbours, so the network forming may effect the conductivity as reported by Denton *et al.* [11] in the case of  $V_2O_5-P_2O_5$  glasses. During the co-evaporation of  $V_2O_5/B_2O_3$ , the  $B_2O_3$  may cause some structural changes in the composite films and an Anderson-type localization process may occur. Because of such a localization, the conductivity of co-evaporated  $V_2O_5/B_2O_3$  thin films will decrease compared to that for the evaporated thin films of simple  $V_2O_5$ . This agrees with our experimental results as is clear from Figs 1 and 4. By co-evaporating  $B_2O_3$  with  $SiO_x$ , Hogarth and Wright [21] observed that co-evaporated  $SiO_x/B_2O_3$  film showed better dielectric properties than simple evaporated  $SiO_x$  films. Vardhan *et al.* [27] have also observed that the addition of  $B_2O_3$  to  $SiO$  results in an increase in the dielectric constant of  $SiO$  films. They have suggested that some structural changes brought about by  $B_2O_3$  in  $SiO-B_2O_3$  composite films could be responsible for such a change in the dielectric constant. Mikoda *et al.* [28] reported that the addition of  $B_2O_3$  to glasses containing  $PbF_2$  reduced the dielectric loss by suppression of crystallization.

The  $I(V)$  characteristics for co-evaporated 70%

$V_2O_5/30\% B_2O_3$  (300 nm) thin films as shown in Fig. 4, indicated a non-linear type of behaviour (almost exponential) for higher fields. When the data of Fig. 4 are replotted as  $\log I$  against  $V^{1/2}$ , a straight line is obtained for higher fields which is an indication of Schottky or Poole–Frenkel type of conduction mechanism. So it can be concluded that the conduction mechanism through composite thin films of  $V_2O_5/B_2O_3$  in MIM structure also follows the same relationship as in Equation 4. The experimental value of  $\beta$  for 70%  $V_2O_5/30\% B_2O_3$  (300 nm) thin films as determined with the help of Fig. 5 and Equation (1) is found to be  $1.35 \times 10^{-5} \text{ eV m}^{1/2} \text{ V}^{-1/2}$ . In addition, the theoretical value of the barrier-lowering coefficient in the case of the Poole–Frenkel effect ( $\beta_{PF}$ ) for the higher frequency (40 kHz) dielectric constant (28.5) is  $1.42 \times 10^{-5} \text{ eV m}^{1/2} \text{ V}^{-1/2}$  and that for the Schottky effect is  $7.1 \times 10^{-6} \text{ eV m}^{1/2} \text{ V}^{-1/2}$ . From comparison of the experimental value of  $\beta$  with those values calculated for the Poole–Frenkel coefficient and the Schottky coefficient, respectively, we again favour a Poole–Frenkel type of conduction mechanism through co-evaporated 70%  $V_2O_5/30\% B_2O_3$  thin (300 nm) films. A similar behaviour has been observed previously for other compositions of co-evaporated  $V_2O_5/B_2O_3$  films. It is worthwhile to mention that the co-evaporated thin films with a molar content of  $B_2O_3$  greater than 40% were unstable because of their hygroscopic behaviour. A similar behaviour has also been observed by Sharma *et al.* [19] for  $V_2O_5-B_2O_3$  glasses. This suggests that during the co-evaporation of  $V_2O_5/B_2O_3$ , the effect of  $B_2O_3$  may result in the expansion of the structure and the insulating behaviour of co-evaporated  $V_2O_5/B_2O_3$  thin films may be enhanced, compared to that for simple  $V_2O_5$ . Thus the effect of applied field on the lowering of the barrier height in the case of co-evaporated  $V_2O_5/B_2O_3$  films will be less than that for simple  $V_2O_5$  thin films. This is consistent with the increase in the optical band gap of  $V_2O_5/B_2O_3$  with increasing  $B_2O_3$  content which will be reported elsewhere. Therefore the co-evaporated  $V_2O_5/B_2O_3$  thin films should be more insulating than simple  $V_2O_5$  thin films, a conclusion which is in agreement with the present experimental observations. Our results also agree with the observations made by other authors [19, 21, 28, 29].

## 5. Conclusion

The conduction process through an MIM structure of evaporated  $V_2O_5$  and of co-evaporated thin films of  $V_2O_5/B_2O_3$  obeys the Poole–Frenkel type of hopping of electrons from  $V^{4+}$  to  $V^{5+}$  centres. The conductivity of co-evaporated  $V_2O_5/B_2O_3$  films shows a decrease with increasing  $B_2O_3$ , but the films with  $B_2O_3$  contents higher than 40% are found to be unstable. The electrical characteristics of  $V_2O_5/B_2O_3$  films are consistent with their optical behaviour.

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*Received 26 October  
and accepted 8 November 1989*